



Contribution ID: 112

Type: **Poster (by default)**

## Formation of Self-Focused Ion Beam

The formation of self-focused ion beam with a small diameter is proposed. The device for the formation of self-focused ion beam consists of a hollow anode and enveloped anode, separated from the anode by an insulator, gas delivery system. A discharge is supported by the voltage applied between the cathode and anode. The ion beam is self-focused by the spherical emission surface of emitting plasma.

The result of computer simulation of self-focused ion beam production is presented. The device for self-focused ion beam production is described.

### Funding Agency

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Yes

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**Session Classification:** Tuesday

**Track Classification:** Beam Formation, Extraction, Transport, and Diagnostics